

1763

Docket No. 215872US2
IN RE APPLICATION OF: Akira YONEMIZU, et al.
SERIAL NO: 09/986,894
FILED: November 13, 2001
FOR: SUBSTRATE PROCESSING APPARATUS AND SUBSTRATE PROCESSING METHOD

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:
Transmitted herewith is an amendment in the above-identified application.

- ☐ No additional fee is required
☐ Small entity status of this application under 37 C.F.R. §1.9 and §1.27 is claimed.
☒ Additional documents filed herewith: Marked-up Copy

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The Fee has been calculated as shown below:

CLAIMS	CLAIMS REMAINING		HIGHEST NUMBER PREVIOUSLY PAID	NO. EXTRA CLAIMS	RATE	CALCULATIONS
TOTAL	29	MINUS	25	4	x \$18 =	\$72.00
INDEPENDENT	4	MINUS	5	0	x \$84 =	\$0.00
		<input type="checkbox"/> MULTIPLE DEPENDENT CLAIMS			+ \$280 =	\$0.00
		TOTAL OF ABOVE CALCULATIONS				\$72.00
		<input type="checkbox"/> Reduction by 50% for filing by Small Entity				\$0.00
		<input type="checkbox"/> Recordation of Assignment			+ \$40 =	\$0.00
		TOTAL				\$72.00

- ☒ A check in the amount of **\$72.00** is attached.
- ☒ Please charge any additional Fees for the papers being filed herewith and for which no check is enclosed herewith, or credit any overpayment to deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.
- ☒ If these papers are not considered timely filed by the Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

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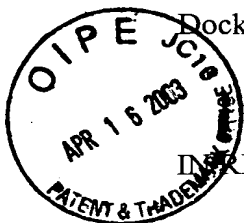


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IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF:

AKIRA YONEMIZU ET AL.

SERIAL NO: 09/986,894

FILED: NOVEMBER 13, 2001

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EXAMINER: MOORE, R

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FOR: SUBSTRATE PROCESSING APPARATUS AND SUBSTRATE PROCESSING METHOD

AMENDMENT UNDER 37 CFR 1.111

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ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

In response to the Office Action mailed January 16, 2003, please amend the above-identified patent application as follows:

IN THE CLAIMS

Please cancel Claims 12 and 15-21 without prejudice or disclaimer.

Please amend Claims 1, 9, 11, and 13 as shown in the attachment. Claims 1, 9, 11, and 13 in clean form are shown below:

1. (Amended) An apparatus disposed adjacent to a main transfer mechanism for processing a substrate, comprising:

a heating process chamber in which a heating process is performed for the substrate;

a load lock chamber, integrally connected to the heating process chamber in a predetermined direction, having an opening closable with a shutter allowing the substrate to